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Attorney Docket: 081468-0302644 Client Reference: P-1698.000-US

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION OF PE FLAGELLO ET AL.

Confirmation Number: 7154

Application No.: 10/698,012

Filed: October 31, 2003

Group Art Unit: 2854

Examiner: Unassigned

Title: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

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Pursuant to 37 C.F.R. 1.56, the attention of the Patent and Trademark Office is hereby directed to the following U.S. patent application(s):

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
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Pt.	Joeri LOF et al.	10/705,783	11/12/2003	Specification Drawings Other: stamped receipt card
PA	Helmar VAN SANTEN et al.	10/743,271	12/23/2003	 Specification Drawings Other: stamped receipt card
(Pt	Johannes C.H. MULKENS et al.	10/743,266	12/23/2003	Specification Drawings Other: stamped receipt card
D7	Klaus SIMON et al.	10/724,402	12/01/2003	 Specification Drawings Other: stamped receipt card
°P2	Joannes T. DESMIT et al.	10/705,804	11/12/2003	 Specification Drawings Other: stamped receipt card
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27	Arno J. BLEEKER	10/715,116	11/18/2003	 Specification Drawings Other: stamped receipt card
27	Bob STREEFKERK et al.	10/719,683	11/24/2003	 Specification Drawings Other: stamped receipt card
P2	Joeri LOF et al.	10/705,816	11/12/2003	 Specification Drawings Other: stamped receipt card
22	Joeri LOF et al.	10/705,805	11/12/2003	 Specification Drawings Other: stamped receipt card

*The Examiner's initials adjacent a citation indicates he/she has considered the cited application relative to the subject application.

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